

Development of Kyoto's X-ray Astronomical SOI pixel sensor

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Publication

| | | |
|------------------|----------------------------------|---|
| Ryu et al. | IEEE NSS 2010, Conf. Record | XRPIX1-CZ -FI |
| Ryu et al. | IEEE TNS 58, 2528 (2011) | XRPIX1-CZ-FI |
| Tsuru et al. | IEEE NSS 2011 | Review |
| Ryu et al. | IEEE NSS 2011, Conf. Record | Event-Driven Readout system |
| Nakashima et al. | IEEE NSS 2011, Conf. Record | XRPIX-ADCI |
| Nakashima et al. | Physics Procedia 37, 1373 (2012) | XRPIX1-FZ-FI |
| Ryu et al. | IEEE TNS 60, 465 (2013) | XRPIX1b-CZ-FI, Inter-pixel cross-talk |
| Takeda et al. | IEEE TNS 60, 586 (2013) | Event-Driven Readout with XRPIX1b-CZ-FI |
| Tsuru et al. | SPIE Astro2012 | Review |
| Nakashima et al. | NIM A, Accepted (2013) | XRPIX2 |

Talk Plan

- X-ray Astronomy
- “XRPIX”
Kyoto’s X-ray Astronomical SOI pixel sensor
- Depletion Layer and Dark current
 - FZ of 2010 and 2012
- Spectral Performance
- Back Illumination
- Coming Soon

Why X-ray Astronomy ?

The Andromeda Galaxy

Cluster of Galaxies

X-ray Image

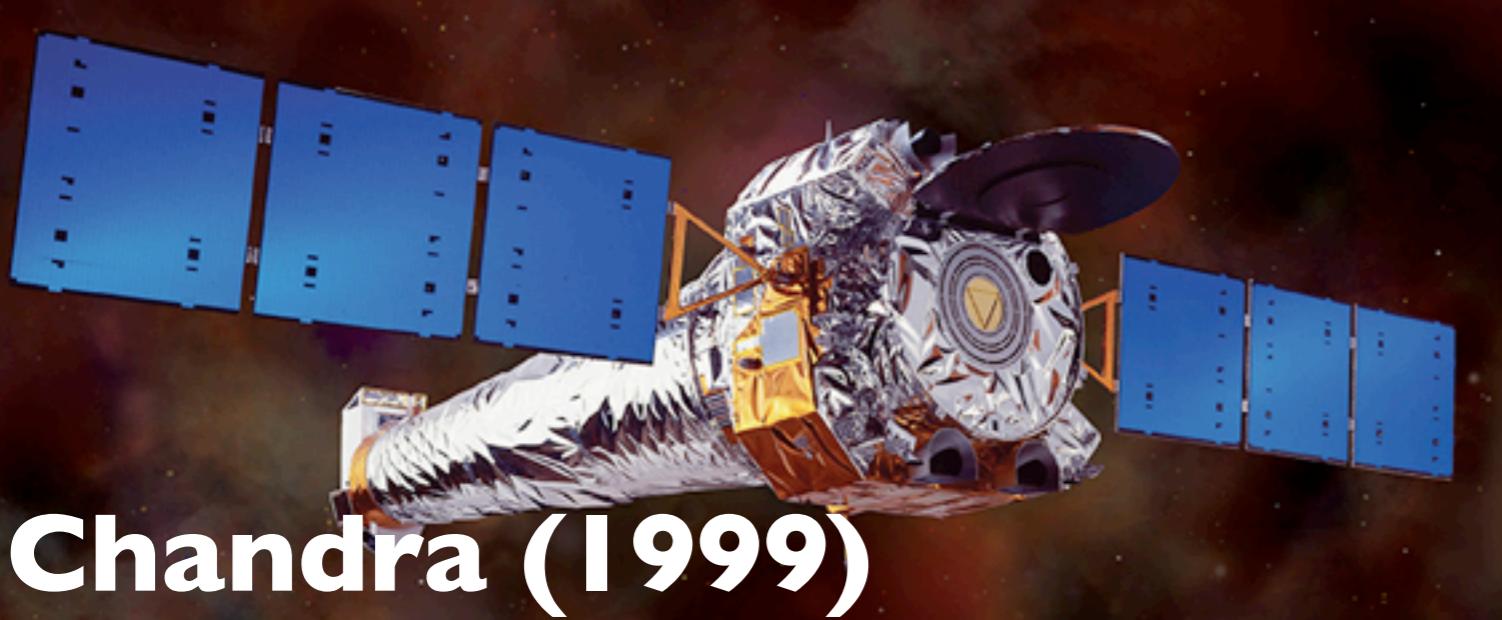
X-ray Image

X-ray astronomy makes the hot and violent universe visible.

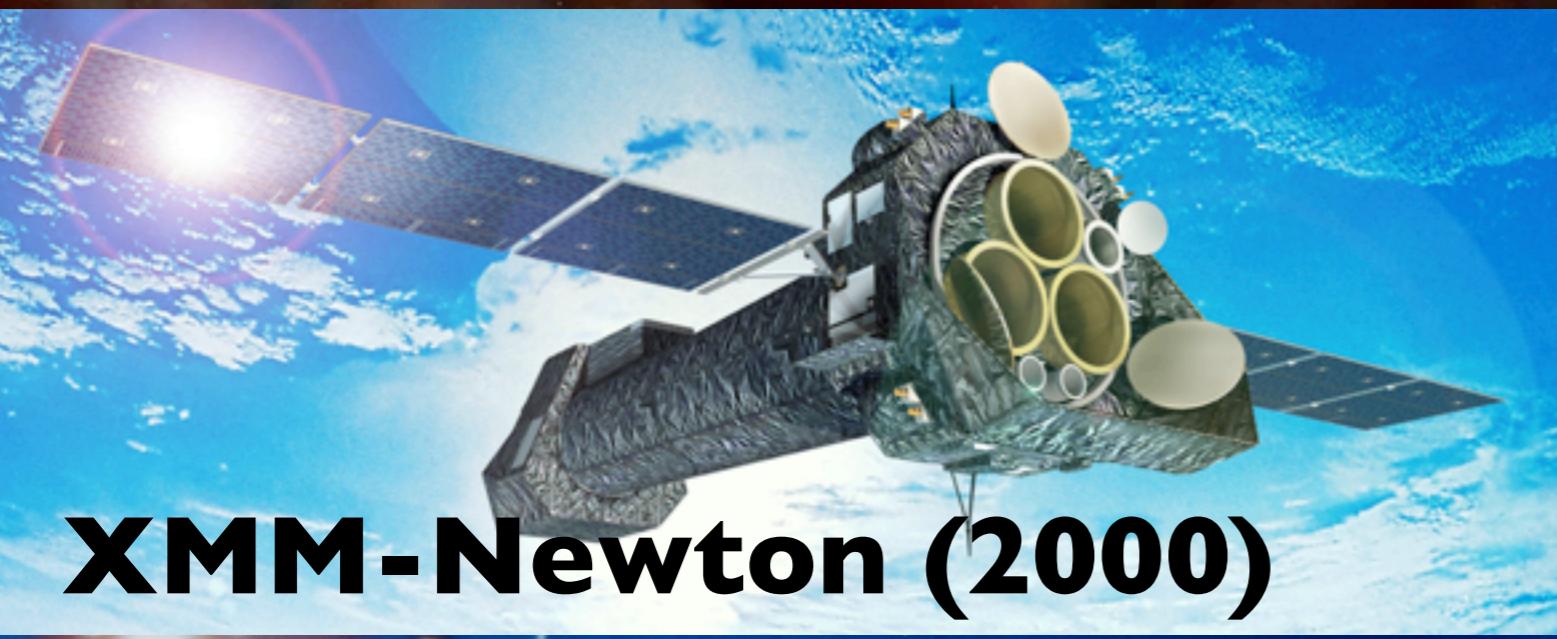
7'

$\sim 10^6$ ly

- Stars like the sun in the optical.
- Blackholes and neutron stars in X-ray.
- Hot plasma = several \times sum of galaxies.
- Most of normal (baryonic) matter in the universe is visible ONLY in X-ray.



Chandra (1999)



XMM-Newton (2000)

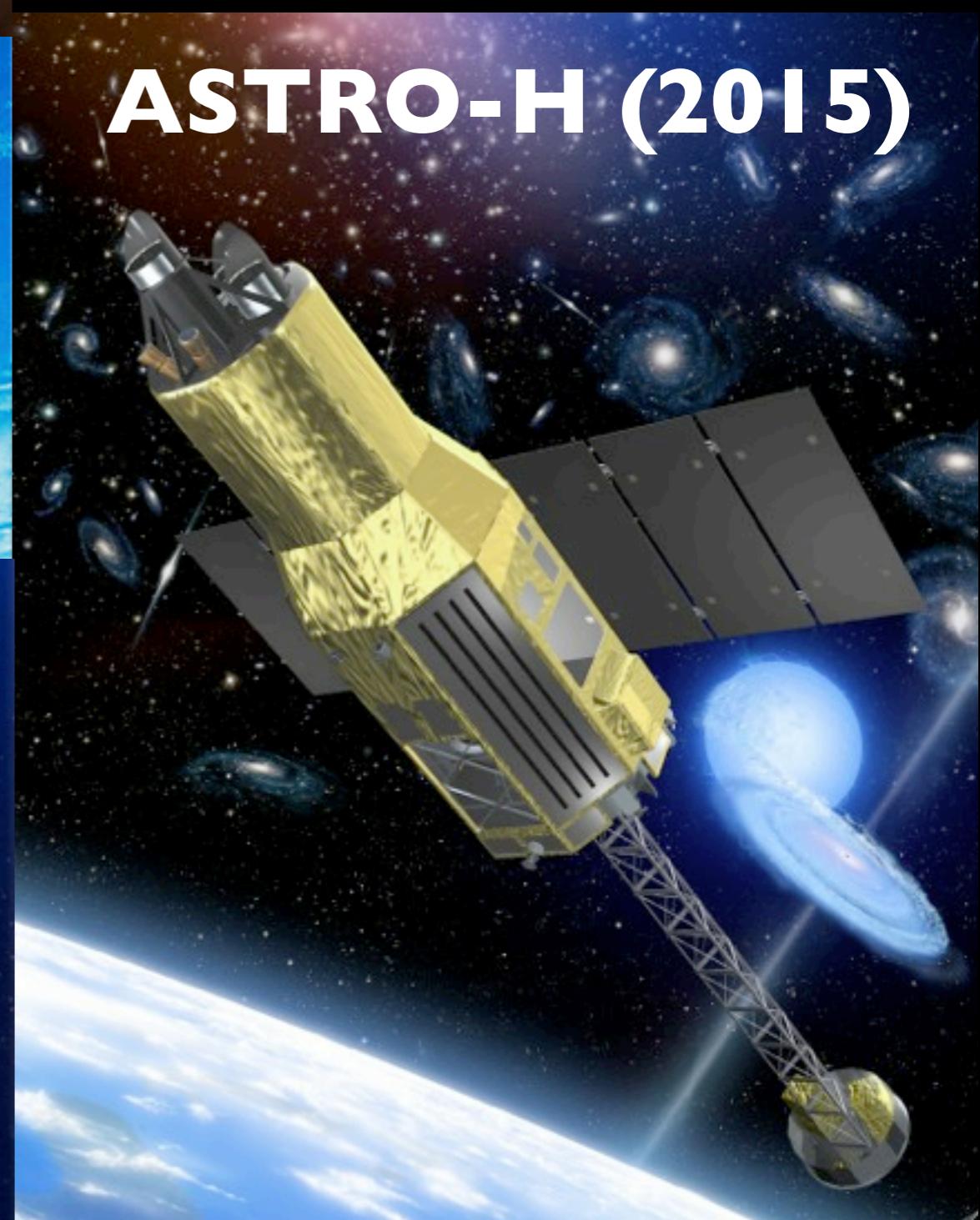


Suzaku (2005)

X-ray CCD

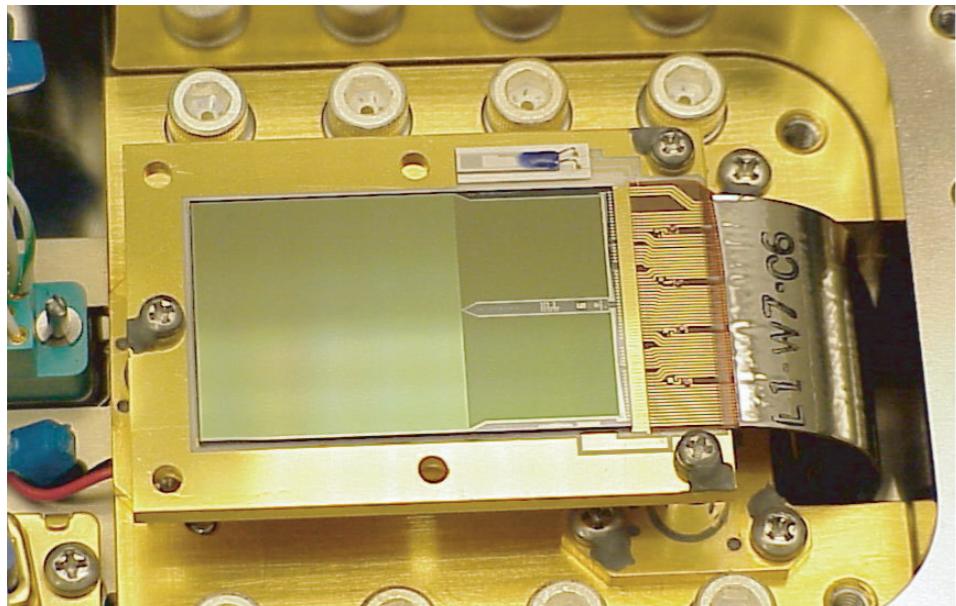
“The” standard Imaging Spectrometer

ASTRO-H (2015)



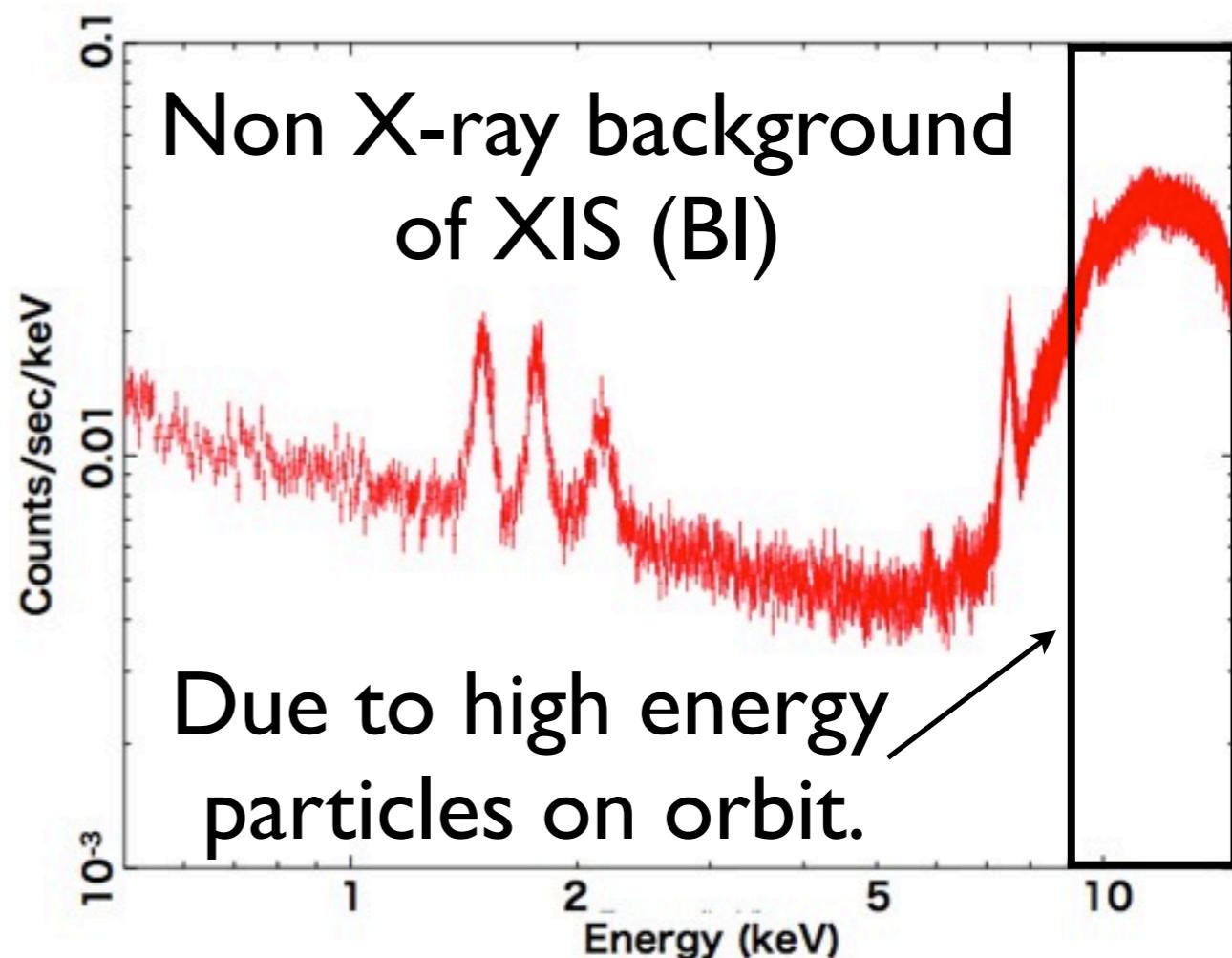
The standard Imaging Spectrometer of modern X-ray astronomical satellites → X-ray CCD

Suzaku 「すざく」 XIS

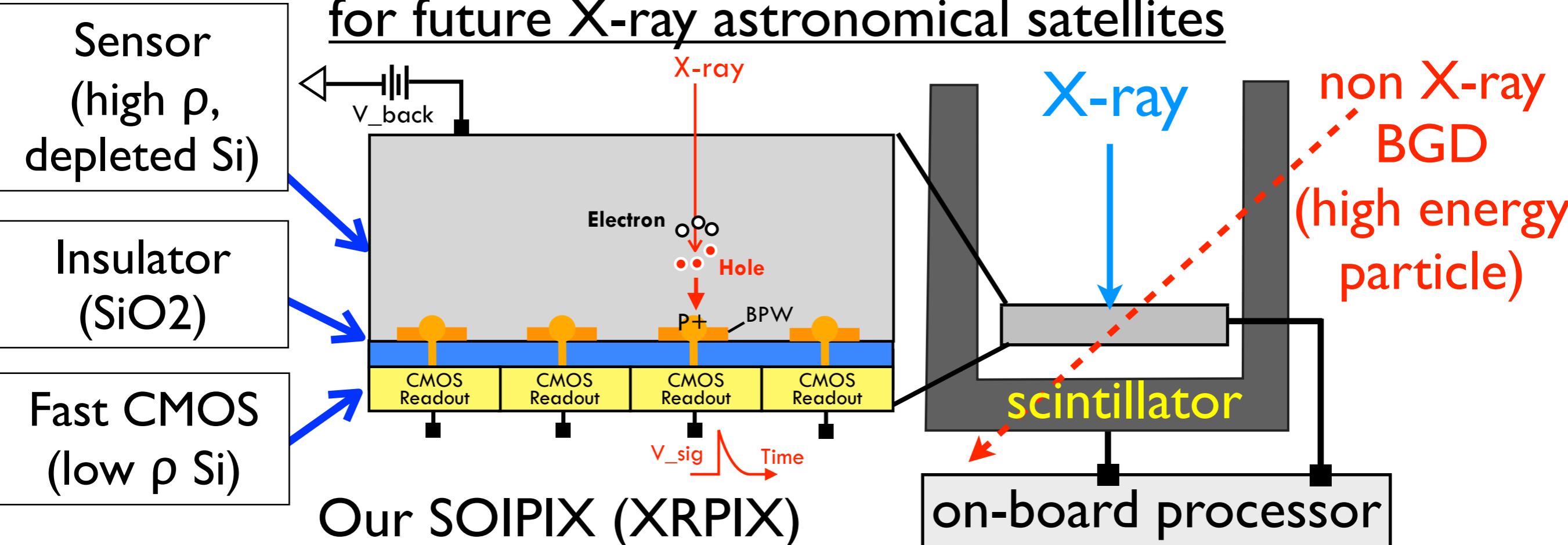


- Fano limited spectroscopy with the readout noise $\sim 3e^-$ (rms).
- Wide and fine imaging with the sensor size of $\sim 20\text{-}30\text{mm}$ pixel size of $\sim 30\mu\text{m}^2$

- **Non X-ray background** above 10keV is too high to study faint sources.
- **The time resolution** is too poor ($\sim \text{sec}$) to make fast timing obervation of time variable sources.



“XRPIX” = **Monolithic** SOI pixel sensor
for future X-ray astronomical satellites

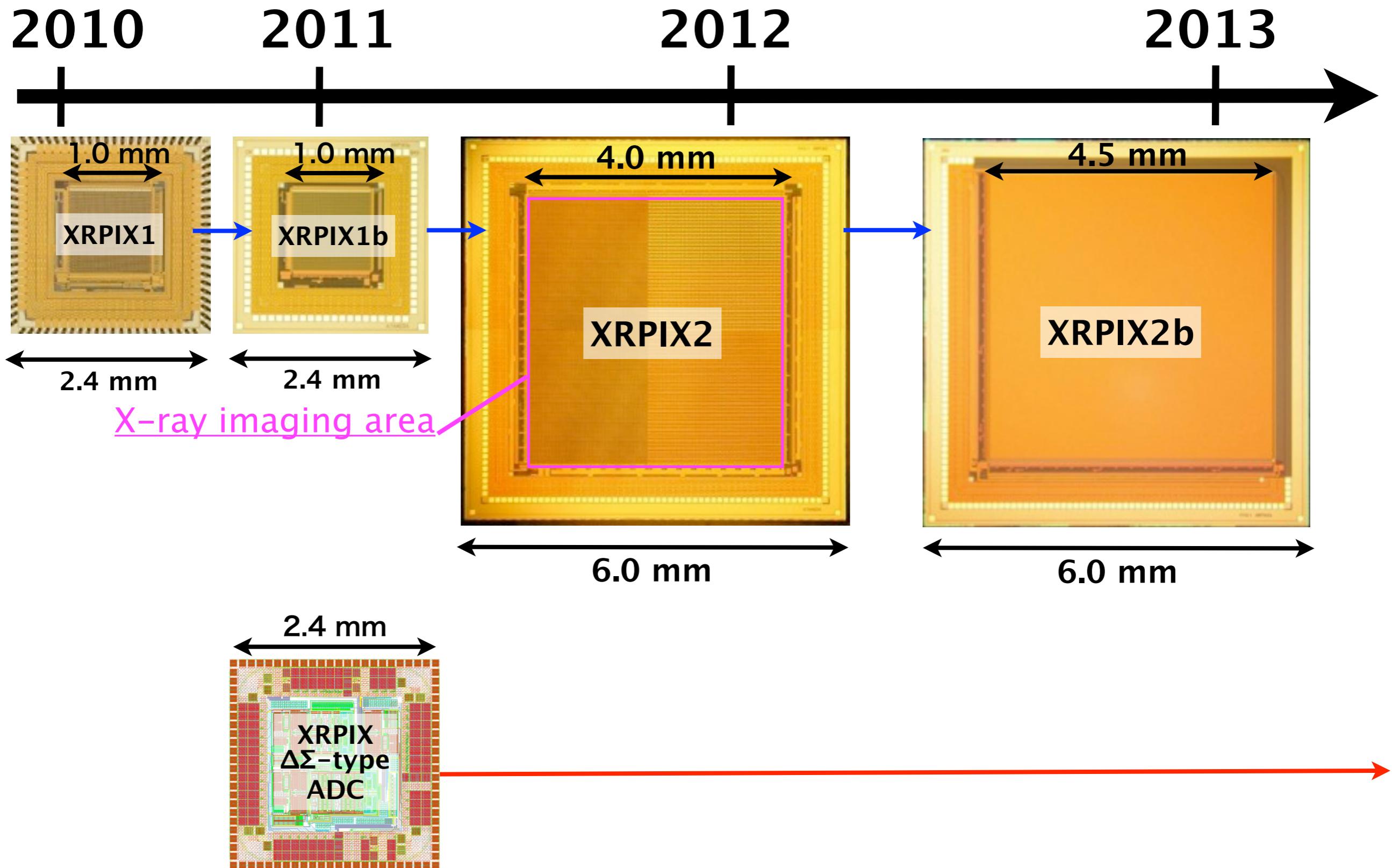


Each pixel has its own trigger and analogue readout CMOS circuit.

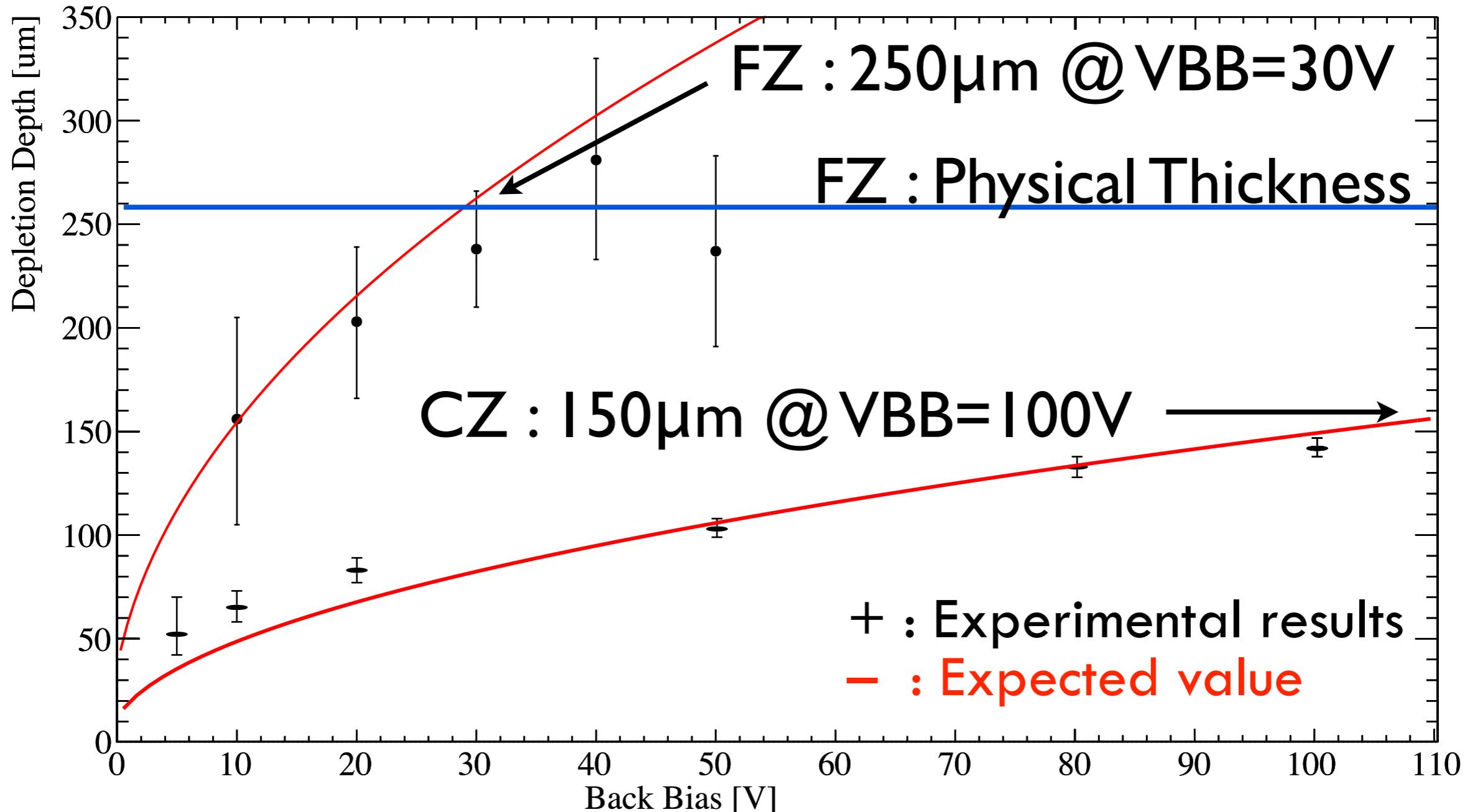
Very low BGD by anti-coincidence
 (1/100 of CCD at 20keV)

| | | |
|--------------|---------------|--|
| Target Spec. | Imaging | area > 25x25mm ² , pixel $\sim 30-60\mu m^2$ (1" @ F=9m) |
| | Energy Band | 0.3-40keV with BI (<0.1 μm), and thick depletion (>250 μm) |
| | Spectroscopy | $\Delta E < 140eV$ @ 6keV, Fano limit (Req.<10e-, Goal < 3e-) |
| | Timing | <1 μ sec |
| | Dark Current | <2pA/cm ² (assuming working T = -40°C) |
| | Function | Trigger signal & pixel address output, built-in ADC |
| | Non X-ray BGD | 5e-5 c/s/keV/10x10mm ² at 20keV (1/100 of CCD) |

XRPIX Series – Road Map –

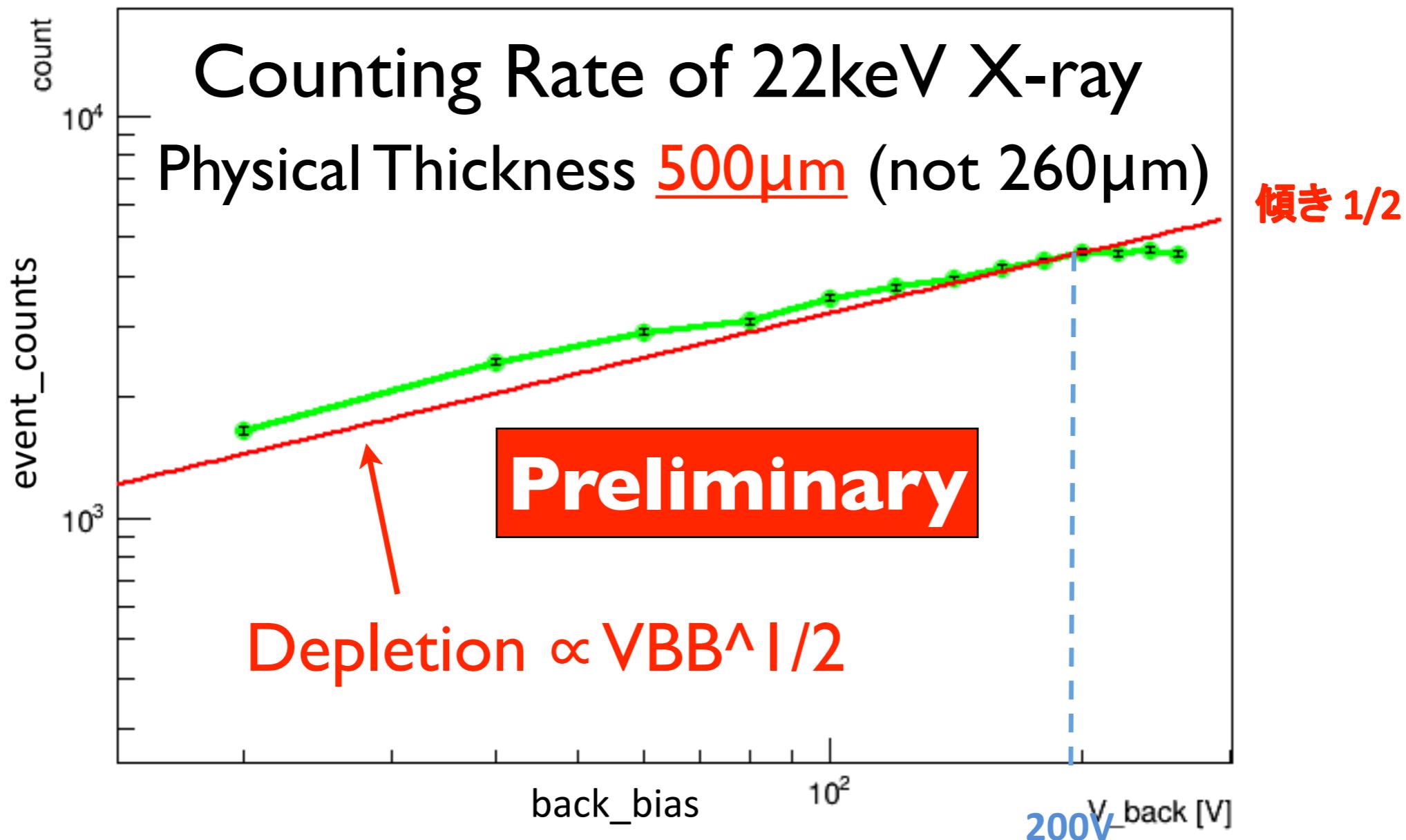


XRPIX1-CZ (0.7k Ω cm), -FZ(2010) (7k Ω cm): Depletion Depth



- Measure the depletion thickness by observing the ratio between the counting rates of two energies X-rays having different attenuation lengths.
- CZ: Depletion thickness of 150 μ m at VBB=100V.
- FZ: Full depletion of 250 μ m is achieved at VBB=30V.

XRPIX Ib-FZ(2012)-FI (7k Ω cm) : Depletion Depth

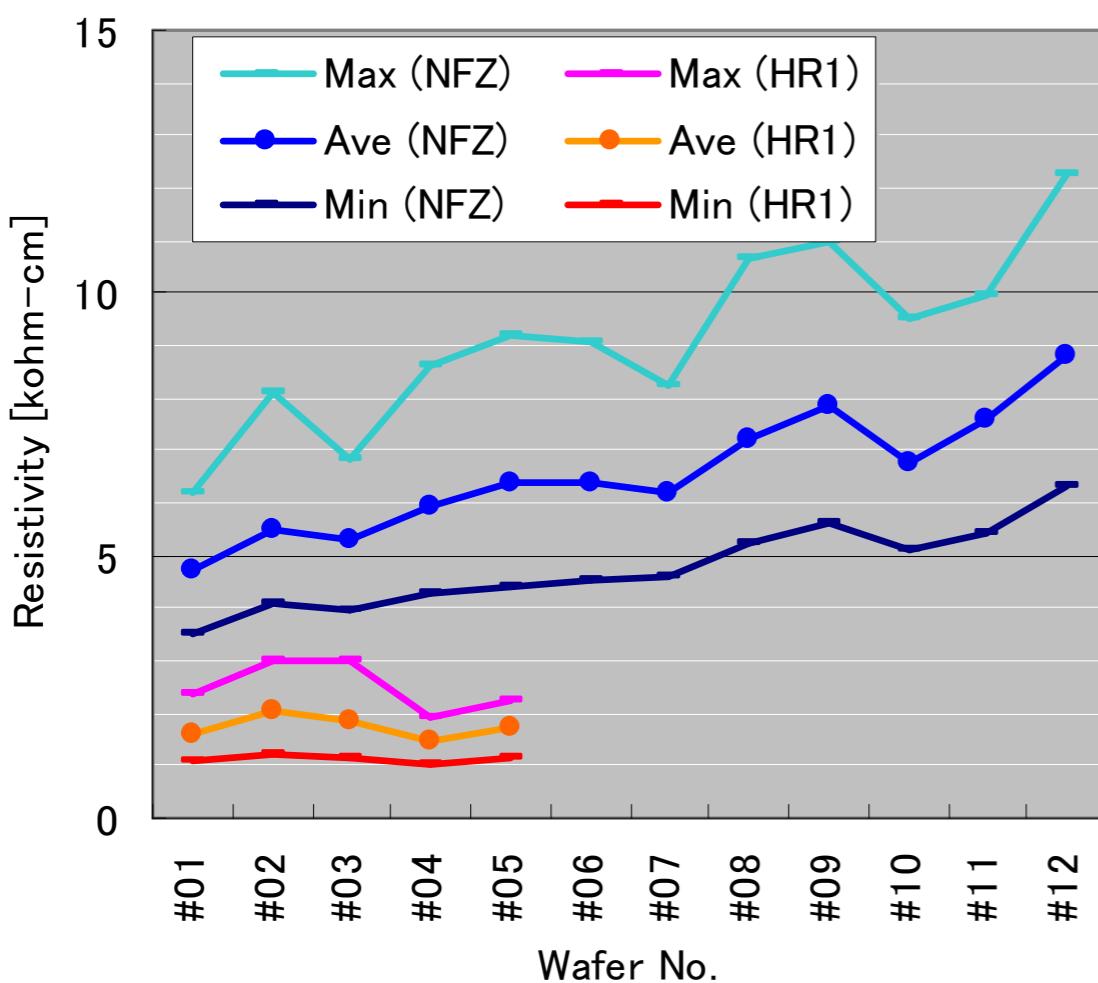


- Counting Rate of 22keV X-ray (Cd-I09) as a function of VBB.
 (Attenuation Length = 1200 μ m > Physical Thickness = 500 μ m.)
- The data follow the expected slope of depletion $\propto V_{BB}^{1/2}$.
- Full Depletion is reached at VBB=200V.

XRPIX Ib-FZ(2012)-FI (7kΩcm) : Depletion Depth

- 500μm @ VBB=200V
→ $\rho = 4\text{k}\Omega\text{cm} < \text{average } (7\text{k}\Omega\text{cm})$
- ρ is different from position to position on a wafer.
- Check which wafer used in this device.

b) 比抵抗のウェハバラツキ



b) MX1542-002JA (N型FZ)

#01

| | | | | |
|-----|-----|-----|-----|-----|
| 4.8 | 4.6 | | | |
| 4.8 | 3.5 | 3.8 | 4.1 | |
| 4.6 | 4.1 | 3.7 | 3.6 | 5.3 |
| 4.2 | 5.1 | 4.2 | 3.9 | 5.8 |
| 4.6 | 4.7 | 4.2 | 4.3 | 6.2 |
| 5.6 | 5.2 | 5.0 | 5.6 | |
| | 5.7 | 6.0 | | |

#12

| | | | | |
|------|------|------|------|------|
| 8.5 | 8.8 | | | |
| 8.2 | 6.9 | 6.8 | 8.2 | |
| 7.8 | 6.3 | 6.9 | 9.2 | 11.1 |
| 8.0 | 7.3 | 7.1 | 8.2 | 10.9 |
| 8.8 | 7.8 | 7.8 | 8.7 | 12.2 |
| 10.5 | 9.9 | 9.7 | 10.8 | |
| | 11.2 | 10.5 | | |

XRPIXI/Ib-FZ(2010/12)-FI (7kΩcm) : Dark (Leak) Current

II

- XRPIXI-FZ(2010)
 - Wafer Thickness 260μm

Consists of two components.

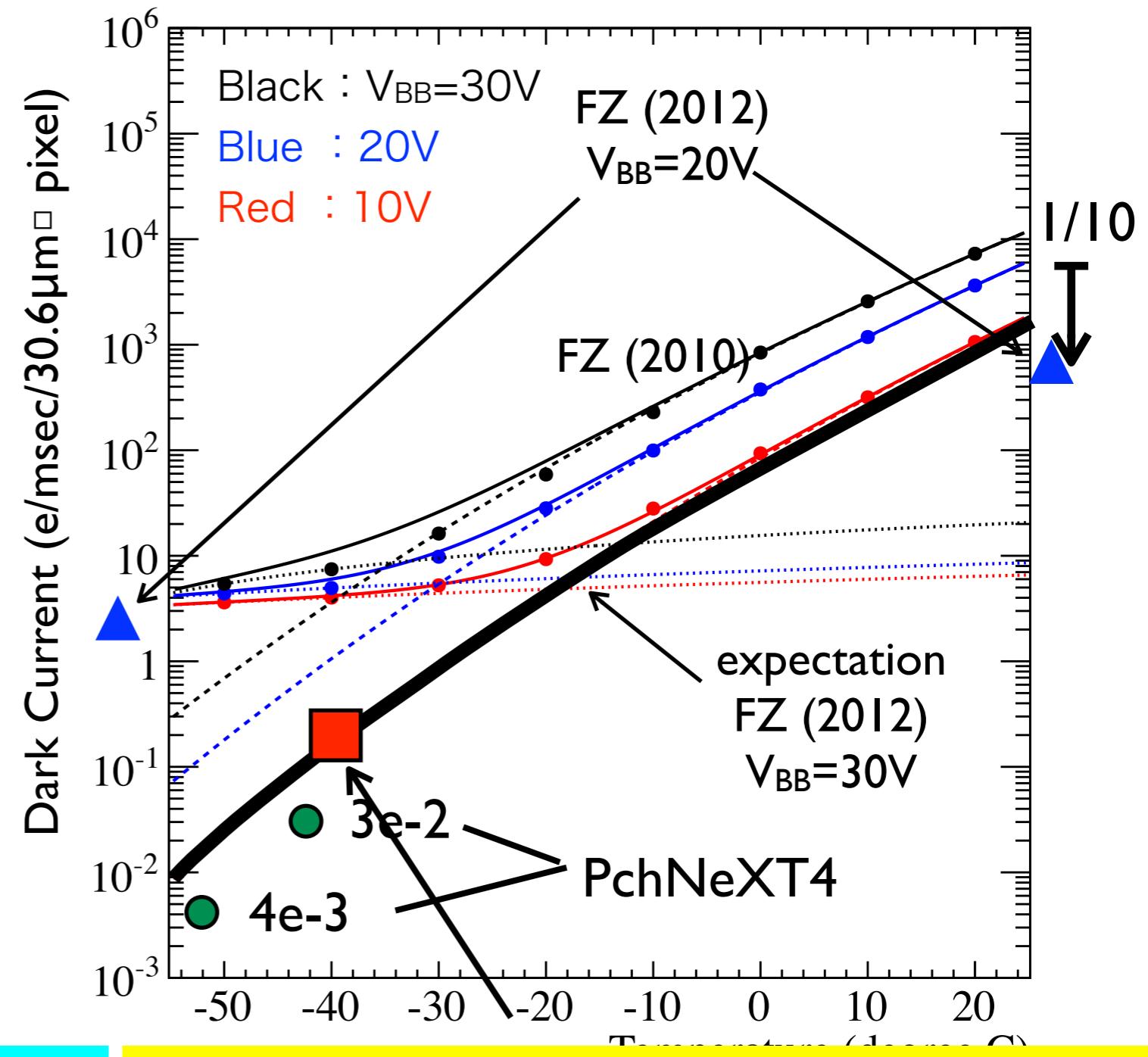
(1) Depend on T and V_{BB}.
generation in depletion layer.

(2) Almost Constant.

$$10e/\text{msec} = 1.6\text{fA}$$

⇒ Next Slide

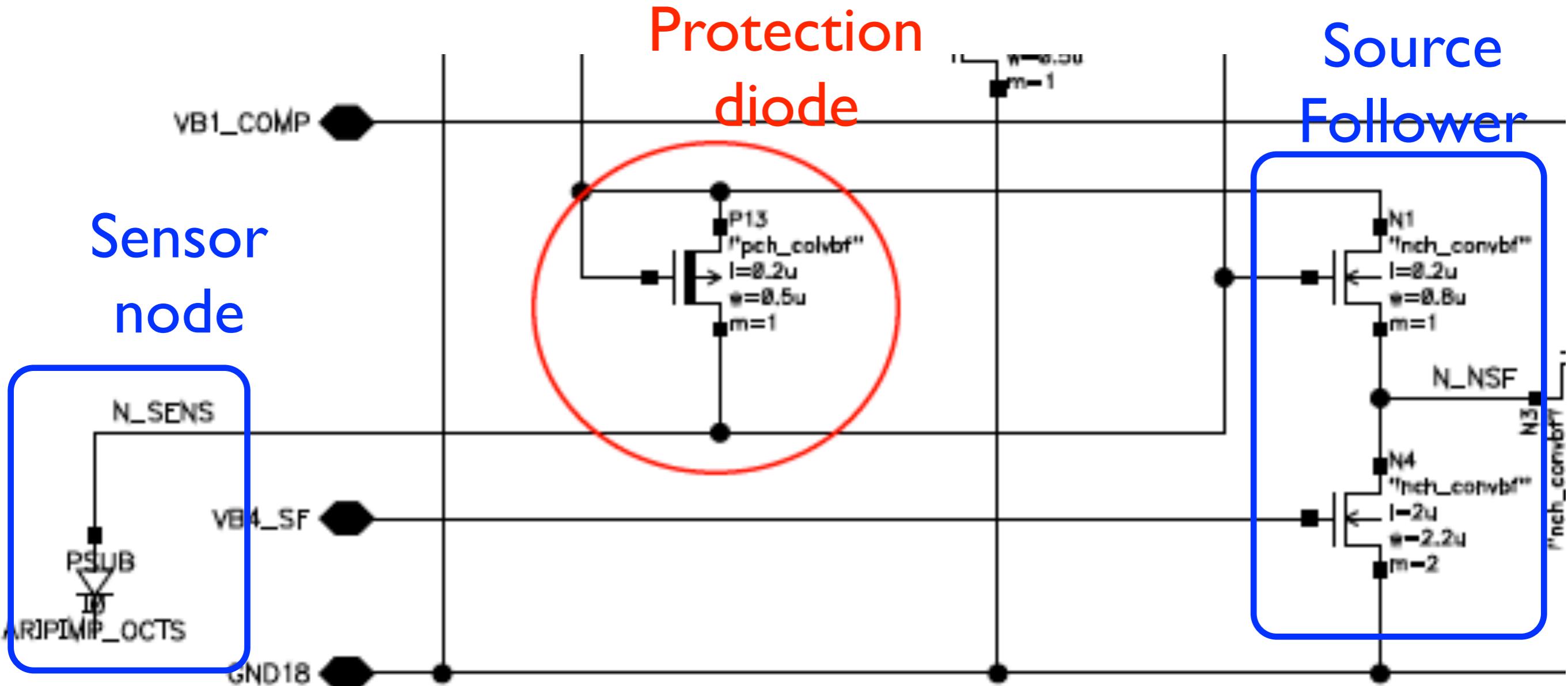
- XRPIXIb-FZ(2012)
 - Dark is 1/10 of FZ(2010)
(at the same V_{BB})



Eliminating the constant component
⇒ reach the target specification.

Target Spec. at -40°C (depletion 250μm)
= 0.1e/1msec/30.6μm² = 2pA/cm²

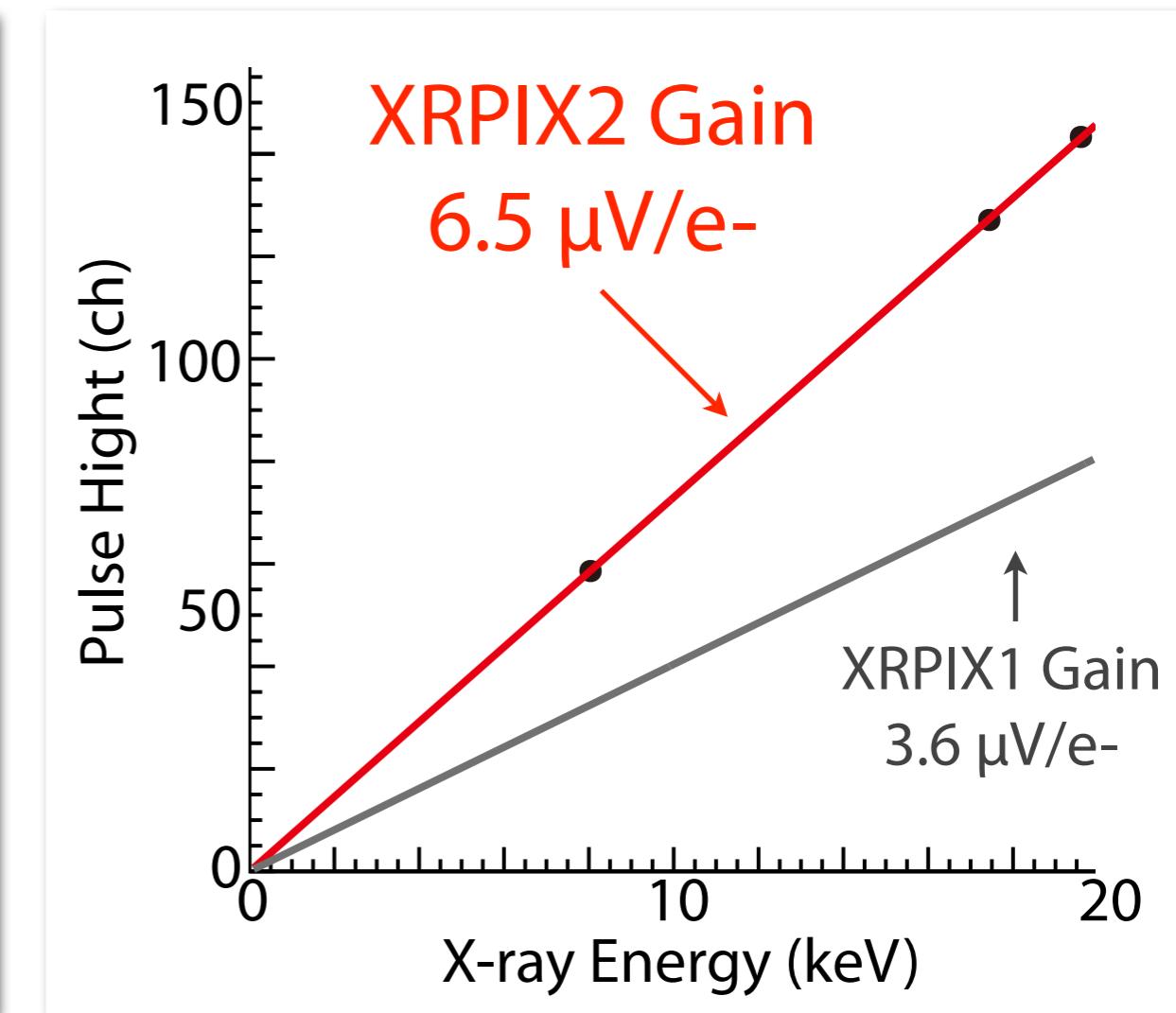
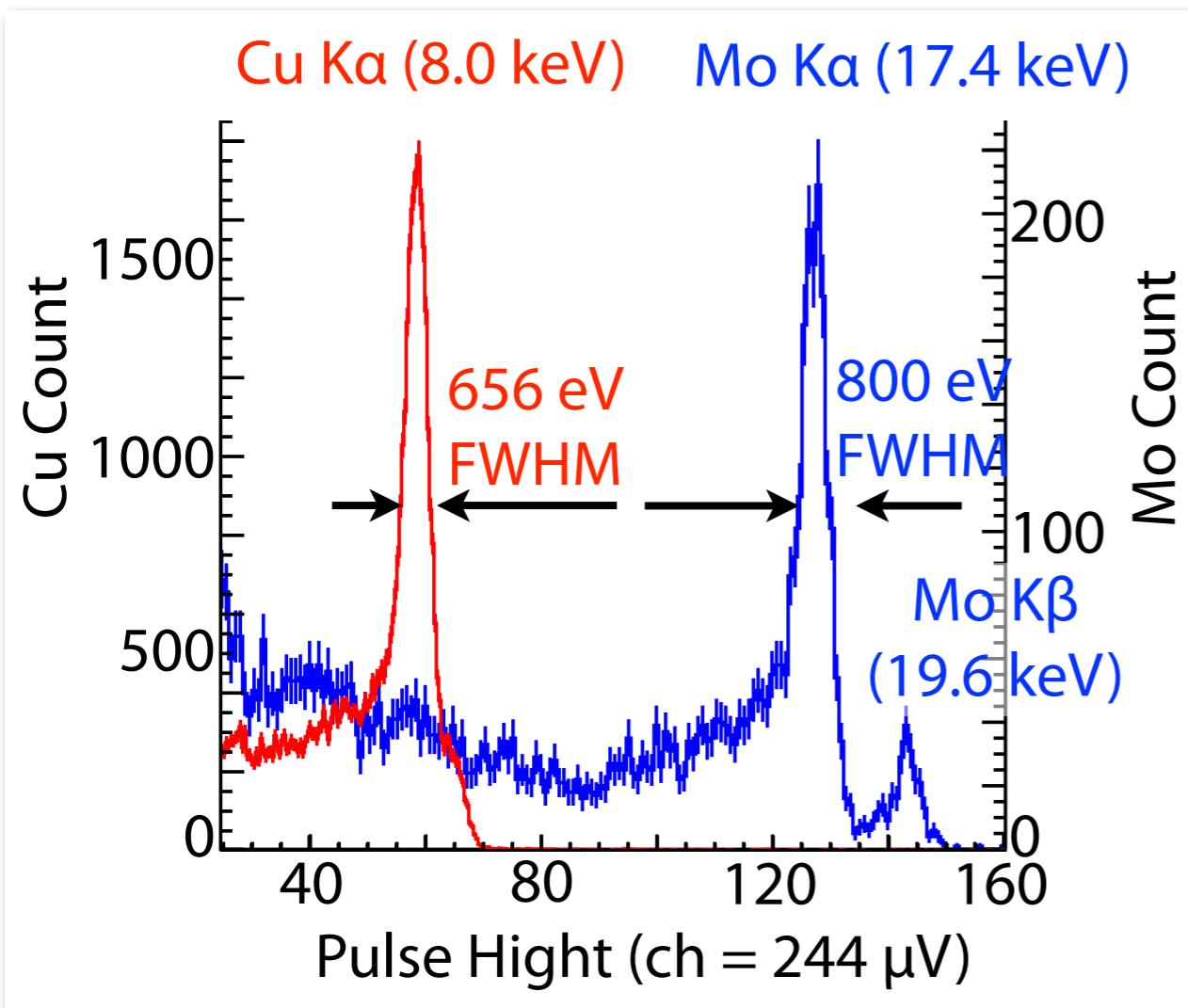
Leak Current from Protection Diode (Arai-sensei)



- Simulation shows leak current from PMOS used as a protection diode at the sensor node is $2\text{fA} = 12.5\text{e}/\text{msec}$.
- Possibly explains the constant component.
- Gate length of the PMOS = $0.2\mu\text{m} \rightarrow 1\mu\text{m}$.
⇒ Reduce leak current $2\text{fA} \rightarrow 0.02\text{fA}$.

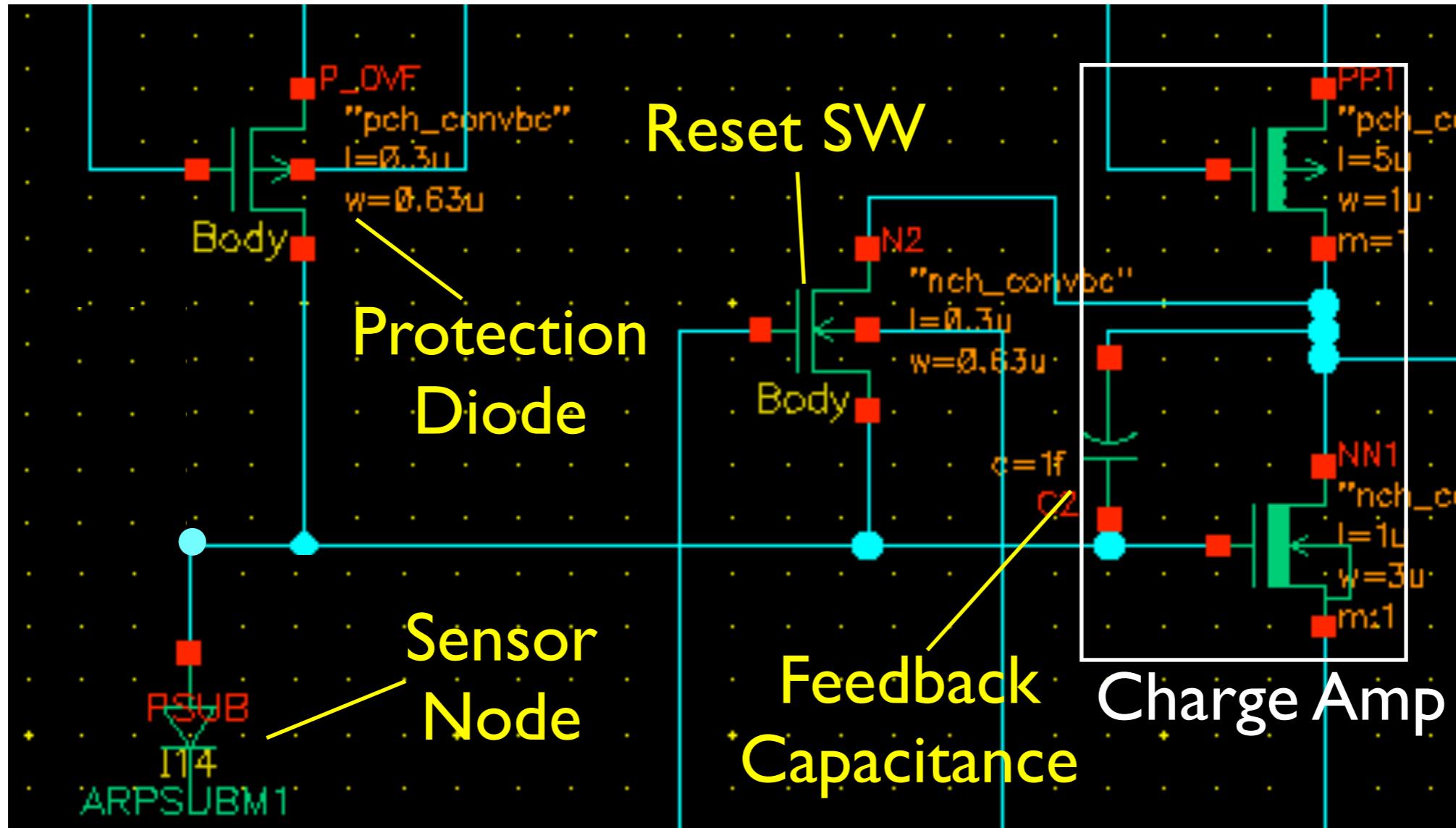
XRPIX2-CZ-FI (Small Pixel) : Spectrum

I3



| | Observed | Readout Noise | Fano Noise | Pixel-Pixel Gain Dispersion 1% | Sum |
|---------------|----------|-----------------------------|------------|--------------------------------|--------|
| Cu K α | 656 eV | 548 eV (FWHM) 64 e-(rms) | 139 eV | 255 eV | 620 eV |
| Mo K α | 800 eV | | 205 eV | 553 eV | 805 eV |

Coming Soon I / Pre Amp in Each Pixel

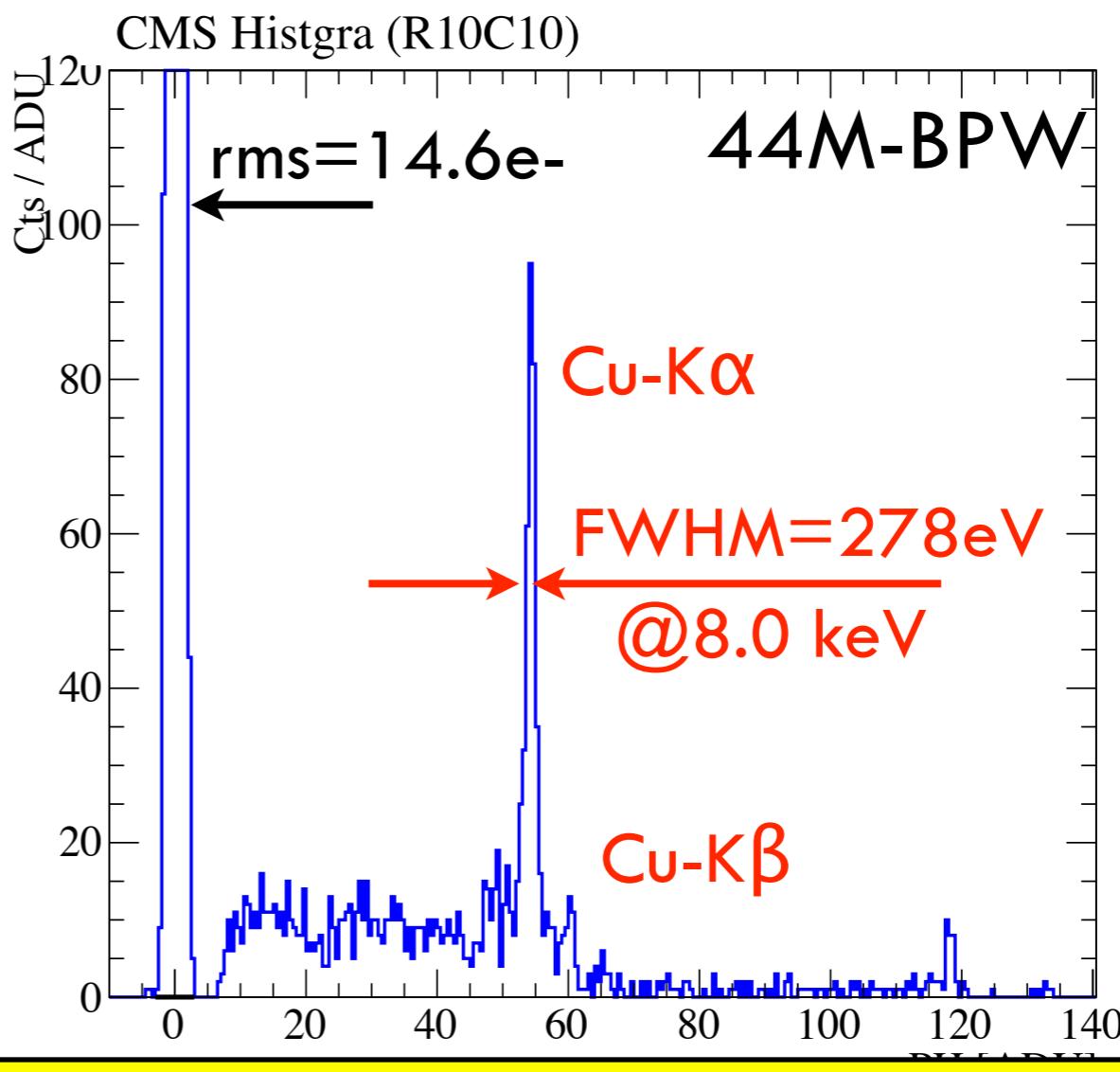
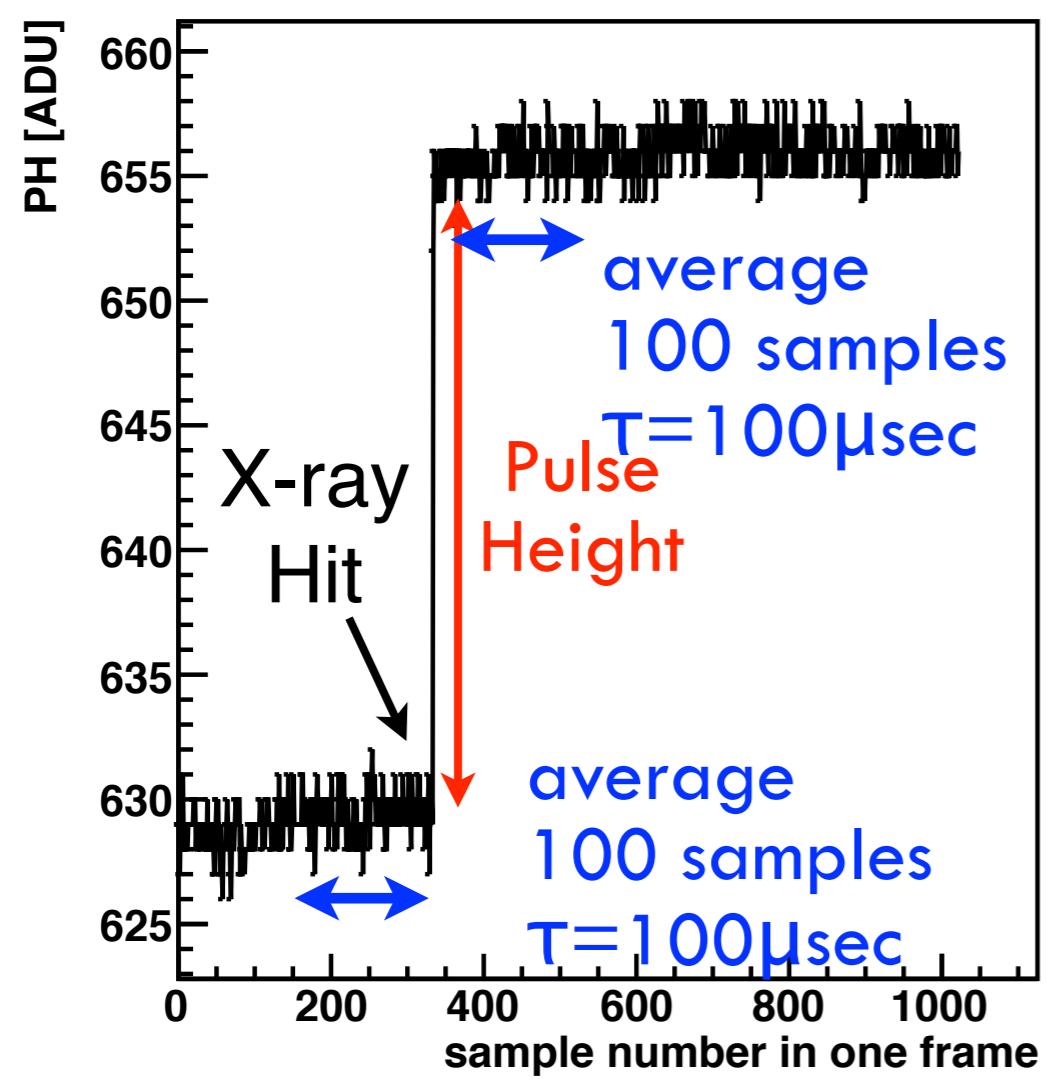


XRPIX3

- A charge sensitive amp in every pixel in order to increase the gain.
- This is basically the same amp used in PIXOR.
- Gain $\sim 100 \mu\text{V/e}$, higher by a factor of ~ 15 .
- Readout noise = 64e (rms) $\rightarrow \sim 4\text{e}$ (rms).

XRPIX1b-CZ : Single Pixel Readout

- In order to study the soft X-ray performance.
- Observe the waveform of analogue output from a single pixel by fixing the readout address without clocking (Single Pixel Readout like a SSD).
- Detect an X-ray as a “step” and measure the pulse height. → X-ray spectrum.
- No reset during the measurement → Free from the reset noise
- Reduce noises other than the reset noise by introducing LPF.
 $\text{high_v(100 samples average)} - \text{low_v(100 samples average)}$ → LPF with $\tau=100\mu\text{s}$



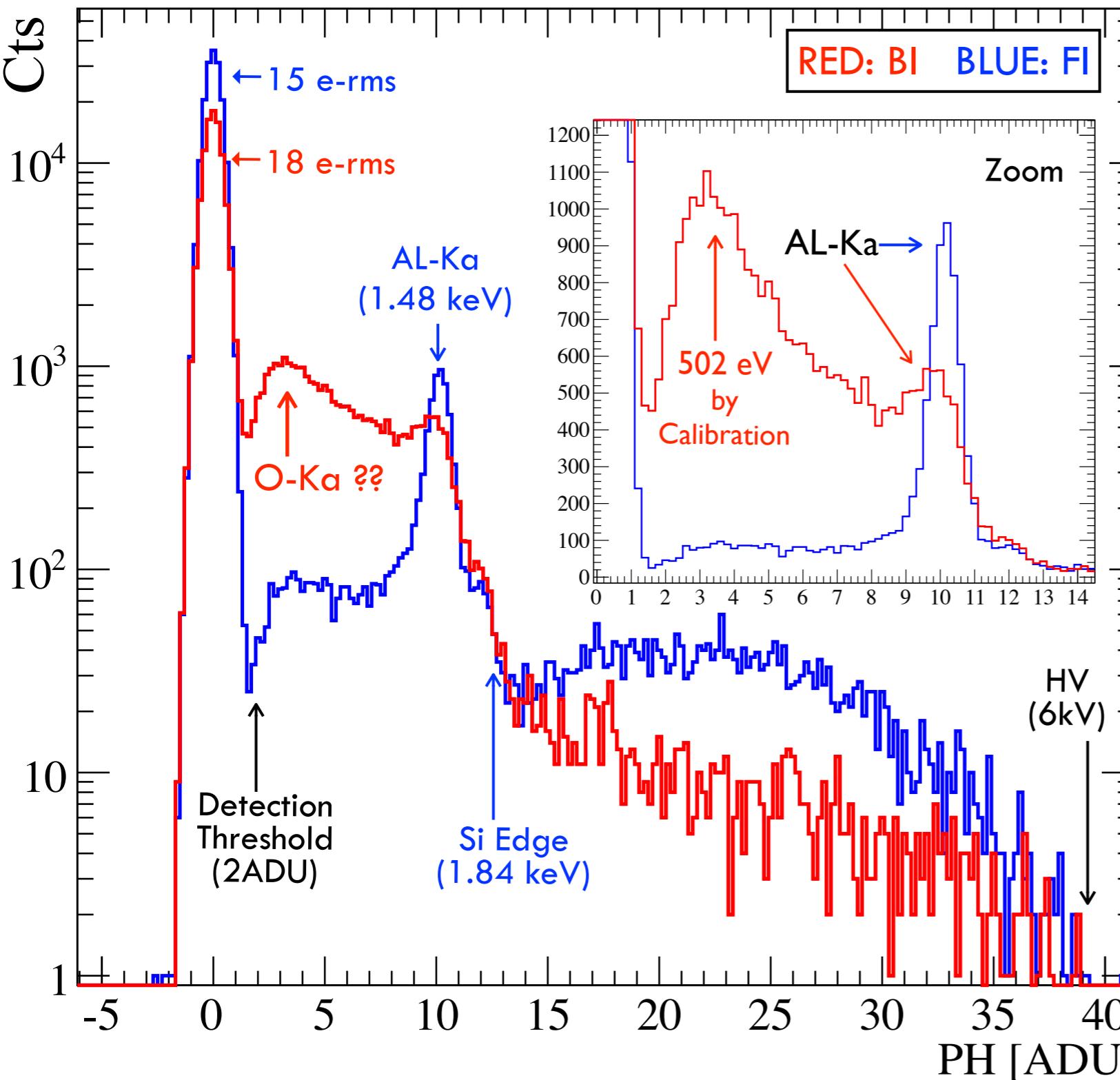
Nakashima
et al.,
2012,
Physics
Procedia
37, 1373
Ryu et all,
2013, IEEE
TNS 60,
465

$\Delta E = 278\text{eV} @ 8.0\text{keV (FWHM)}, \text{ readout noise} = 14.6\text{e (rms)}$

XRPIX Ib-CZ-FI/BI (100μm): Spectra in Single Pixel Readout (2011.11.22) ¹⁶

Target= Al_2O_3 , Front-I, Back-I, $V_{\text{tube}}=6 \text{ kV}$,

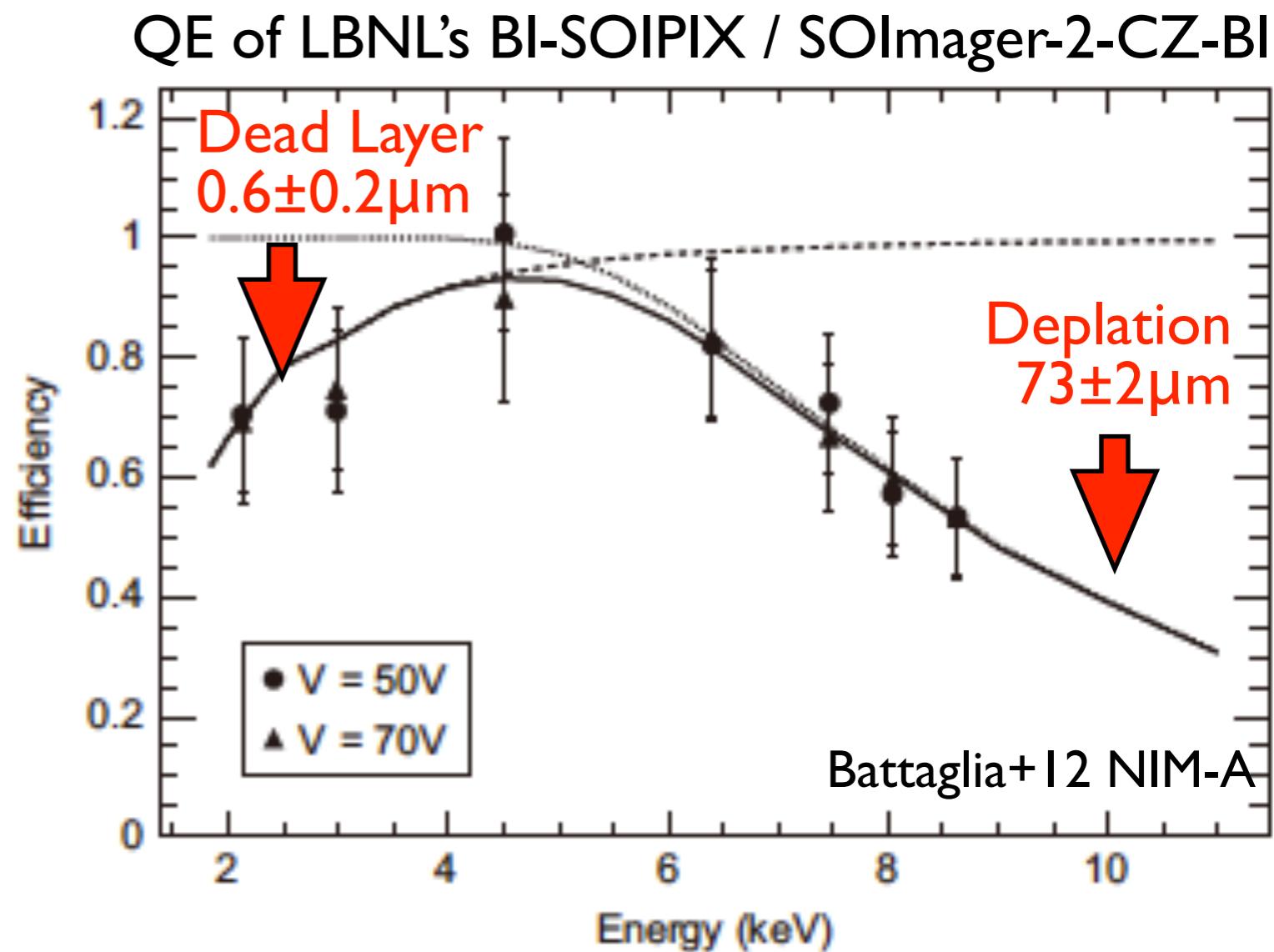
$V_{\text{bias}} = 100 \text{ V}$, Temp= -50°C , Hit Threshold= 2 ADU, Exposure= 400 sec, PIX=R10C10, 2us_sample, 300 μs_ave



- Back illumination type.
- X-ray generator (target = Al, 6kV).
- Al-K + Bremss (+O-K from Al_2O_3 ?)
- ΔE (FI) = 188eV, ΔE (BI) = 351eV (if line)
- Absolute and relative X-ray Fluxes are uncalibrated.
→ QE and dead layer thickness are unknown.

Coming Soon 2 / “Pizza Process”

- Pizza Proc. is the back side process developed by LBNL.
- CZ-Bl with Back-thinned to $70\mu\text{m}$.
- A thin phosphor layer is implanted.
- Dead Layer : $0.6\pm0.2\mu\text{m}$



Pizza Process to FZ devices of XRPIX

- The Pizza proc. is now being made at LBNL.
- Evaluation of low energy X-ray spectral performance.

Summary

- We have been developing monolithic SOI sensor ‘XRPIX’ for future X-ray Astronomical Satellites.
- It contains the function of trigger signal output for the anti-coincidence, which realizes very low non-X-ray BGD.
- We successfully developed the test devices with the depletion thickness of $\sim 250\mu\text{m}$.
- Under going
 - Improvement of the readout noise.
 - Reduction of dark current.
 - Test with new back side process (Pizza Proc.).



A-R-Tec
Analog and RF Technologies